

EpiCentre Questionnaire

Contact Details

Establishment

Address

Contact Name

Email Address

Tel Number

Date

EpiCentre Series Selection

EC-I In-line design

Select EC-I

Insertion length (mounting flange to substrate centre)

Standard 240mm

Other (mm)

(please specify below)

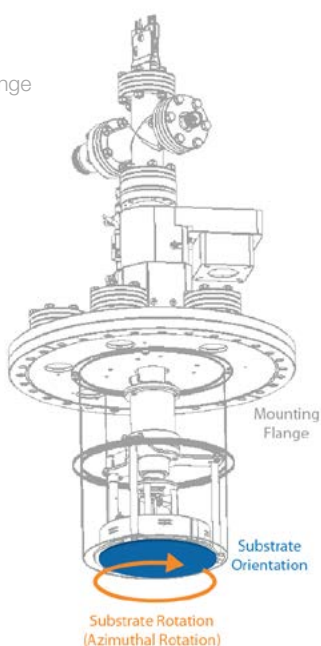
Stage orientation

Vertical - substrate facing up

Vertical - substrate facing down

Other (non-standard option - please specify below)

Tick if you require
Glancing Angle Deposition



EC-I mounting flange required

CF200/10" OD

CF250/12" OD

CF300/14" OD

CF350/16.5" OD

Other (non-standard option - please specify below)

EC-I substrate size (check all that apply)

2"

100mm

150mm (CF250, CF300 & CF350 flanges only)

200mm (CF300 & CF350 flanges only)

Other (non-standard option - please specify below)

Substrate will be: bare wafer in a holder

EC-R Right-angled design

Select EC-R

Insertion length (mounting flange to substrate centre)

Standard 280mm

Other (mm)

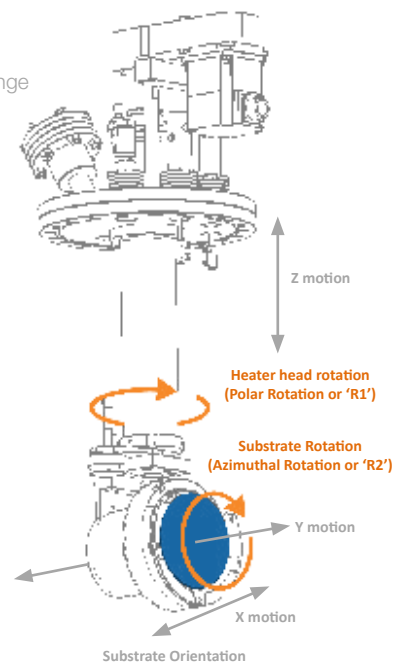
(please specify below)

Stage orientation

Vertical

Horizontal

Other (non-standard option - please specify below)



EC-R mounting flange

CF150/8" OD

CF200/10" OD

CF250/12" OD

Other (non-standard option - please specify below)

EC-R substrate size (check all that apply)

2"

3"

100mm (CF200, & CF250 flanges only)

150mm (CF250 flange only)

Other (non-standard option - please specify below)

Substrate will be: bare wafer in a holder

EpiCentre Configuration & Options (see page 3 for heating element selection)

EC-I Configuration

Note: standard EC-I configuration selected - click options to select an alternative.

Substrate biasing	None (substrate earthed) DC/RF biasing (option)
Substrate rotation	No rotation required Stepper motor 24V DC motor (option) SmartMotor™ (option) No motor (option)
Substrate rotation speed	20rpm (recommended) Other (max 60rpm) rpm
Rotation controller	None Supplied (option)
Cradle lift/lower to aid sample transfer	25mm pneumatic Manual hand wheel (option)
Cradle Rotation Home Sensor	Fitted (standard) Removed (option)
How will samples be transferred?	Manually at atmosphere Transfer arm under vacuum
Deposition height adjustment	None 50mm (option) 100mm (option) 150mm (option) Actuation Manual Motorised Motor controller None Supplied (option)
Substrate shutter	None (Dynamic option available with deposition height adjustment) Manual shutter (option) Motorised shutter (option) Pneumatic shutter (option)
Heater Shields	Molybdenum shields Inconel shields (option)
Deposition Shielding	None Supplied (recommended with bias option and CVD type applications)

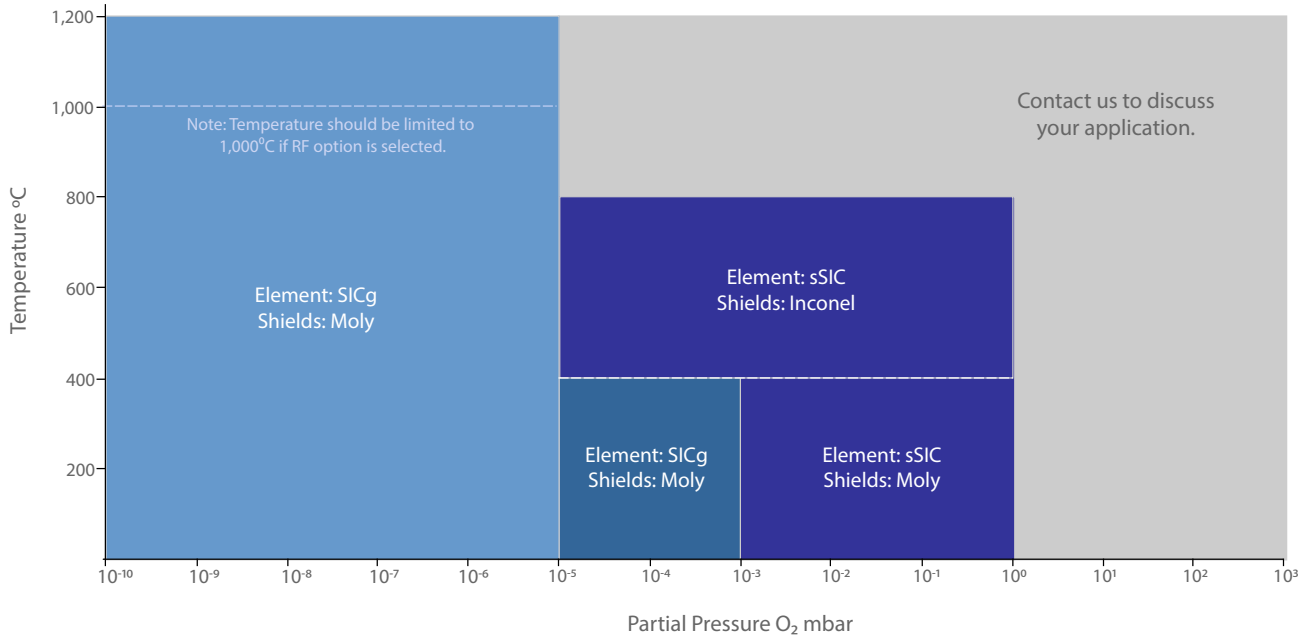
EC-R Configuration

Note: standard EC-R configuration selected - click options to select an alternative.

Substrate biasing	None DC/RF biasing (option)
Polar (primary) rotation	Manual Stepper motor (option) No motor
Substrate (azimuthal) rotation	No rotation required Manual (option) Stepper motor (option) 24V DC motor (option) No motor (option)
Substrate rotation speed (if substrate rotation option selected)	20rpm (recommended) Other - please specify rpm
Rotation controller(s) (tick if required)	Polar controller Azimuthal controller
Rotation Home Sensor (tick if required)	Polar home sensor Azimuthal home sensor
How will samples be transferred?	Manually at atmosphere Transfer arm under vacuum
Z-shift adjustment	None Required (option) mm Actuation Manual Motorised Motor controller None Supplied (option)
XY motion	None Required (option) mm Actuation Manual Motorised Motor controller None Supplied (option)

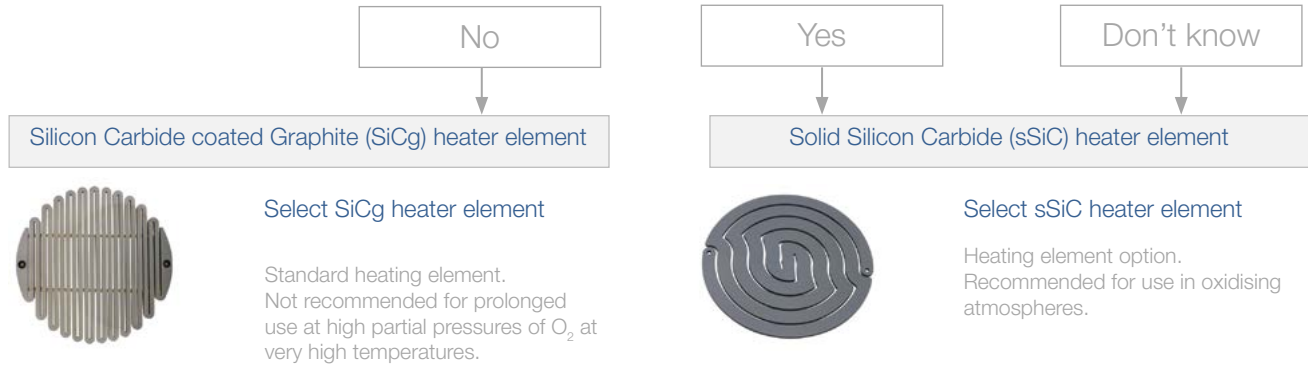
EpiCentre Heater Selection (required for both EC-I and EC-R series)

Element & Shield Material Recommendations



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Does the intended process involve the use of high partial pressures of O₂?



Thermocouple choice

Type K	Quantity required
Type C	One Two

Temperature controller & power supply

None required
Supplied (option)

Application Details (required for both EC-I and EC-R series)

To ensure that you receive the correct configuration of EpiCentre it is essential to provide as much information on the potential applications as possible.

What is the application?

What substrate materials will you be using?

What is the process chamber's ultimate (base) pressure?

What maximum temperature at base pressure do you wish to heat the substrate?

How long do you need to maintain this temperature?

If gases or vapours are involved in your process please complete the information below:

	GAS	PARTIAL PRESSURE		MAXIMUM SUBSTRATE TEMPERATURE	DURATION
		mbar	torr		
1					
2					
3					
4					
5					
6					

Are any of the following materials incompatible with your process? (please tick all that apply)

Tantalum
Copper

Molybdenum
Aluminium

Stainless Steel
Inconel

Additional Comments

How we use this information

We use the information you provide in this questionnaire to evaluate your application before quoting an appropriate product specification. As all applications vary and have factors outside of our control, we are not in a position to offer any performance guarantees outside of our standard final test procedures.